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Title of Invention	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER	
Application Number :	10/680783	
Date :	2003-10-06	
First Named Applicant:	Jones William D.	
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Attorney Docket Number:		
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Submitted By:		Elec. Sign.
Thomas B. Haverstock Registered Number: 32571		/tbh/ Attorney

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